

PATTERN DRAWING APPARATUS AND PATTERN DRAWING METHOD
FOR FORMING PATTERNS, THAT HAVE MIRROR IMAGE
RELATIONSHIP TO EACH OTHER WITH RESPECT TO
A SUBSTRATE, ON BOTH SIDES OF THE SUBSTRATE, AND
5 TEST APPARATUS FOR USE IN THE PATTERN DRAWING APPARATUS

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ABSTRACT OF THE DISCLOSURE

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A pattern drawing apparatus for forming patterns,
that have a mirror image relationship to each other with
respect to a substrate, on both sides of the substrate
forms the patterns on both sides of the substrate by
drawing the patterns directly on both sides of the
substrate in accordance with prescribed data by using a
direct drawing means such as a maskless exposure means or
an inkjet patterning means.